DECLARATION FOR PATENT APPLICATION

As a below named inventor, I declare: that I verily believe myself to be the original, first and sole (if only one individual inventor is listed below) or an original, first and joint inventor (if more than one individual inventor is listed below) of the invention in

SEMICONDUCTOR DEVICE HAVING METAL SILICIDE FILMS FORMED ON SOURCE AND DRAIN REGIONS AND METHOD FOR MANUFACTURING THE SAME

the specification of which is attached hereto unless the following box is checked.

was filed on	as Un	nited States	Application
or PCT International Appl	ication No.		, and
was amended on	(if	f applicable)	•

application on which priority is claimed:

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above. I acknowledge the duty to disclose information of which is material to patentability as defined in 37 CFR 1.56. I hereby claim foreign priority benefits under 35 U.S.C. 119(a)-(d) or 365 (b) of any foreign application(s) for patent or inventor's certificate, or 35 U.S.C. 365(a) of any PCT International application which designated at least one country other than the United States, listed below and have also identified below any foreign application for patent or inventor's certificate, or PCT International application having a filing date before that of the

Country	Category	Application No.	Filing Date	Priority Claim
Japan	Patent	2003-077648	March 20, 2003	Yes

I hereby appoint the registrants of Oblon, Spivak, McClelland, Maier & Neustadt, P.C., 1940 Duke Street, Alexandria, Virginia 22314, Customer No. 22850, or any one of them. Send correspondence to Oblon, Spivak, McClelland, Mailer & Neustadt, P. C., 1940 Duke Street, Alexandria, Virginia 22314, Telephone No. (703)413-3000.

I declare further that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true: and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

DECLARATION FOR PATENT APPLICATION

I declare further that my mailing address is at c/o
Intellectual Property Division, Toshiba Corporation, 1-1, Shibaura
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that my citizenship and residence are as stated below next to my name:

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